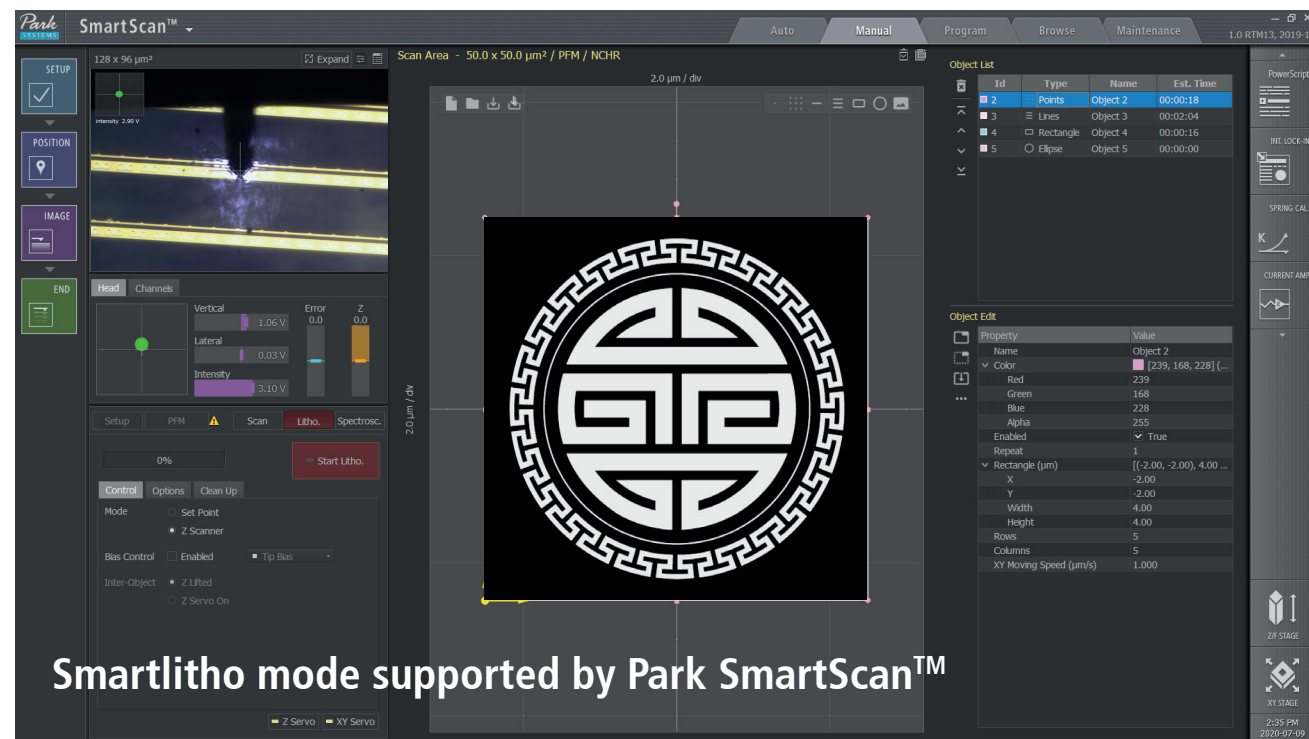
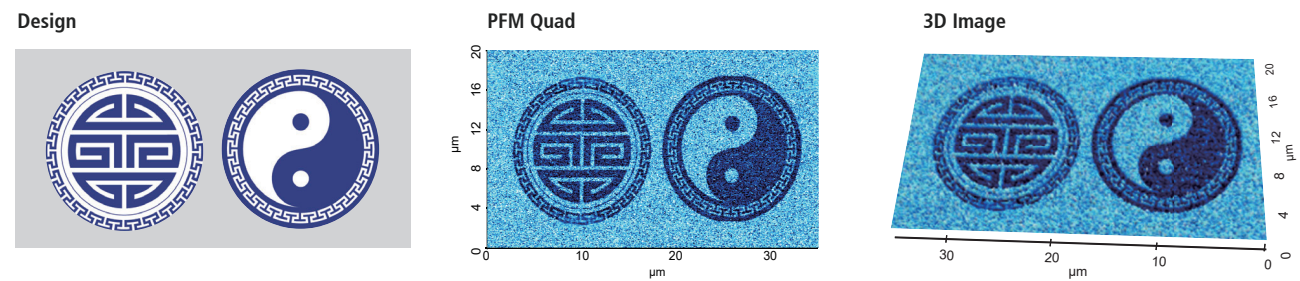


▪ Taegeuk Mark Lithography on PZT



Smartlitho mode supported by Park SmartScan™

Committed to Contribute to Impactful Science and Technological Development

More than 25 years ago, the foundations of Park Systems were laid at Stanford University, where Park Systems' founder, Dr. Sang-il Park, worked in Prof. Calvin Quate's group; the group that invented the world's first AFM. After years of development, Dr. Park introduced the first commercial AFM to the world, thus starting the successful path of Park Systems. With good foresight, a superior product and keen business acumen, Park has positioned themselves as the dominant industry leader in AFM Nanoscale Metrology and in 2020, Park Systems will roll out their most exciting line of AFM products in their history.

Park Systems continuously strives to live up to the innovative spirit of its origin. Throughout its long journey, the company has been committed to provide advanced, accurate, and reliable AFM instrumentation, with revolutionary features such as True Non-Contact™ mode and PinPoint™ Nanomechanical AFM. Cutting-edge AFM automation features, like SmartScan™, make Park Systems AFMs not only extremely easy to use, but they also enable users to obtain outstanding results faster, more efficiently, and more accurately.

**Park Systems**  
Enabling Nanoscale Advances

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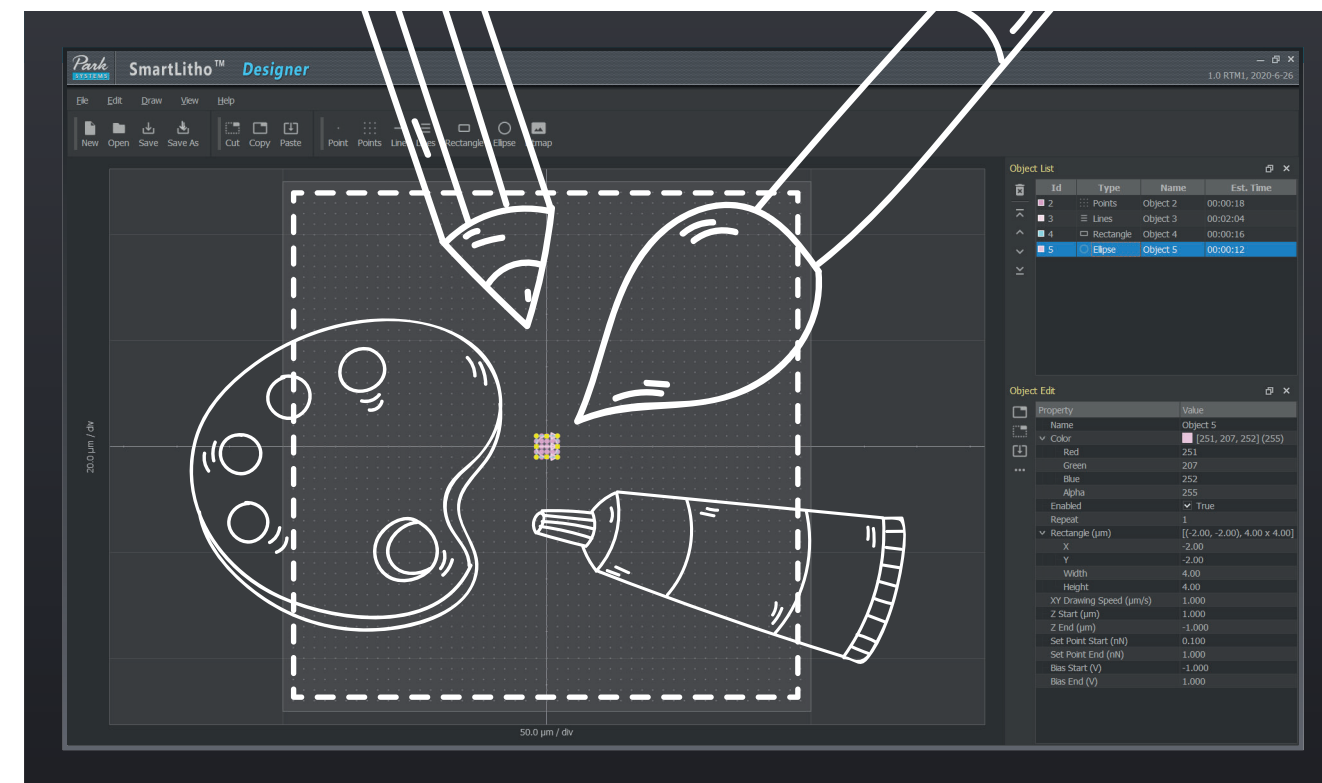


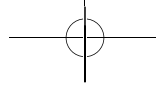
ATOMIC FORCE MICROSCOPE



Park SmartLitho™

The next generation nanolithography and nanomanipulation software combining powerful tools with an easy user interface





Nanolithography

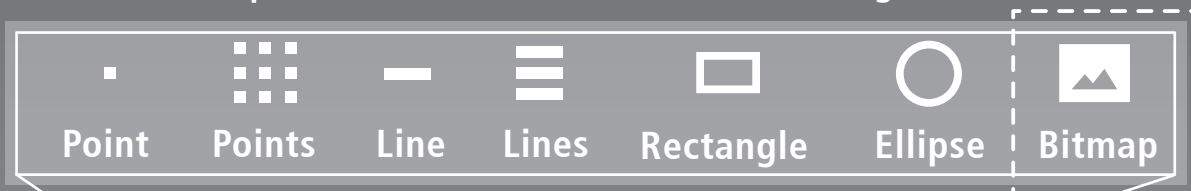


Nanomanipulation

## The easiest operating software available for nanolithography and nanomanipulation

Park SmartLitho, enabled by SmartScan is an AFM based platform that performs nanolithography and nanomanipulation on materials, electrical and electronics devices, nanotechnology and other areas of research.

Park SmartLitho provides a stand-alone convenient drawing editor.

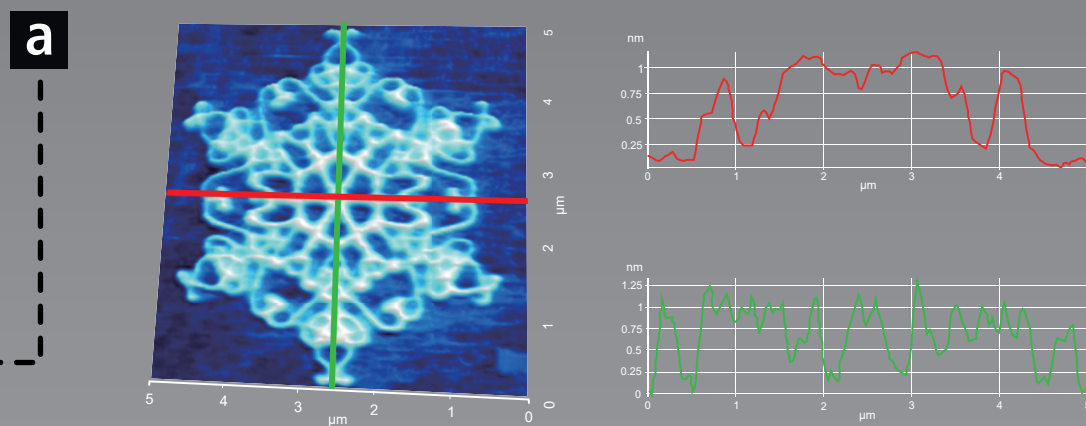


Park SmartLitho software has a variety of lithography modes, supports both Vector mode and Raster mode and operates on the SmartScan platform, which has an easy user interface, and provides a stand-alone convenient drawing editor.

**Park SmartLitho™**

The screenshot shows the 'SmartLitho™ Designer' interface. The main workspace displays a collection of white Christmas ornaments on a black background. A red dashed circle highlights one of the ornaments. To the right, the 'Object List' and 'Object Edit' panels are visible. The 'Object Edit' panel shows the following properties for 'Object 5' (an Ellipse):

Property	Value
Name	Object 5
Color	[251, 207, 252] (255)
Red	251
Green	207
Blue	252
Alpha	255
Enabled	True
Repeat	1
Rectangle (μm)	[[-2.00, -2.00], 4.00 x 4.00]
X	-2.00
Y	-2.00
Width	4.00
Height	4.00
XY Drawing Speed (μm/s)	1,000
Z Start (μm)	1,000
Z End (μm)	-1,000
Set Point Start (nH)	0,100
Set Point End (nH)	1,000
Bas Start (V)	-1,000
Bas End (V)	1,000



Christmas Ball Lithography on Si

